

Voltage readout from a piezoelectric intracochlear acoustic transducer implanted in a living guinea pig

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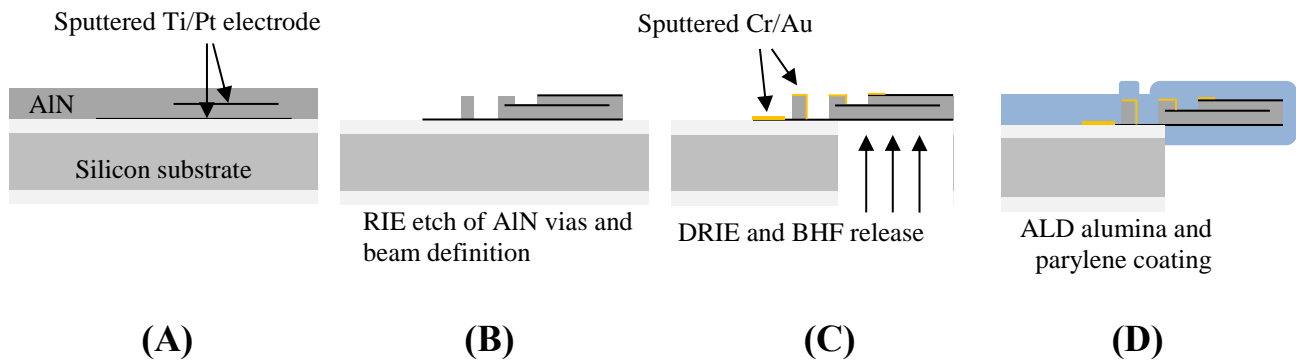


Fig. S1. MEMS fabrication process. (A) AlN deposition and Ti/Pt electrode layer deposition and patterning. (B) RIE etch of the AlN layers to define beam dimensions and create vias to the middle and bottom electrode layers. The top AlN layer was overetched as described in the Methods. (C) Cr/Au deposition for circuit layout connection, followed by DRIE and BHF release. (D) Waterproof coating that consists of ALD alumina and parylene conformal coating after device release.